

A MEMS BODY FLUID FLOW SENSOR

Ellis Meng¹, Sascha Gassmann², and Yu-Chong Tai¹

¹California Institute of Technology, Pasadena, CA 91126, USA

²ETH Zurich, Institute of Mechanics, CH-8092 Zurich, Switzerland

Abstract

To achieve *in vitro* flow rate measurements of biological fluids in such tasks as hematological studies and urinalysis, a MEMS flow sensor has been developed. Flow sensing is achieved by measuring the forced convective heat transfer from a thermal sensing element to the fluid. Currently, fluid flow down to 10 $\mu\text{l}/\text{min}$ can be detected.

Keywords: Flow sensor, thermal sensing, King's Law

1. Introduction

Heat transfer is the most promising flow sensing principle for measuring very low flow rates ($< 1 \text{ ml}/\text{min}$). Several thermal anemometer type sensors have been introduced in previous work [1-4]. Many use polysilicon thermistors as heating and temperature sensitive elements. Here, a metallic resistive sensing element is placed on a channel wall to sense flow rate. When operated in constant current mode, the convective heat transfer from this element to the fluid can be measured and correlated to flow rate.

2. Sensor Design and Fabrication

Sensors (Figs 1-2) consist of platinum resistors on a parylene membrane over a bulk micromachined silicon channel ($1 \text{ mm} \times .5 \text{ mm} \times 8 \text{ mm}$). This structure prevents resistor contact with the fluid and possible issues with corrosion. Platinum is chosen as the sensor material for its stability, accuracy, and high temperature coefficient of resistivity (TCR). Additional packaging is performed to form fluidic connections using micromachined fluidic couplers [5].

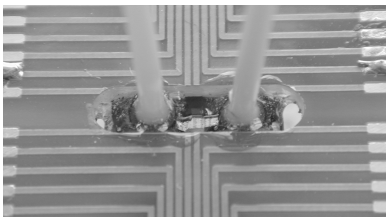


Fig. 1 Flow Channel & Fluidic Connections

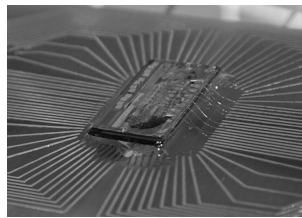


Fig. 2 Sensor Close-Up

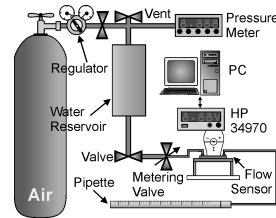


Fig. 3 Flow Testing Setup

3. Experimental

To determine flow rate, the sensor voltage is recorded under constant current (30 mA) while fluid is forced through the device using compressed air. The flow rate is adjusted by a metering valve and calibrated using a stopwatch and precision pipette (Fig. 3).

4. Results and discussion

Temperature calibration and transient behavior of the device under water flow and no flow conditions are shown in Figs 4-6. As expected, the device responds faster to

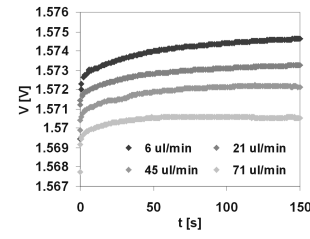
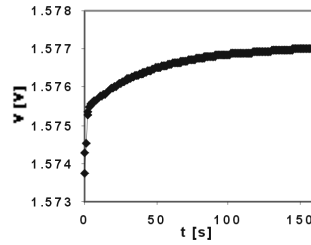
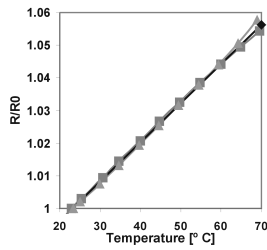


Fig. 4 Temperature Calibration Fig. 5 Transient Response to No Flow Fig. 6 Transient Response to Water Flow

higher flow rates. The transient response has two associated time constants, the first being less than 1 s and the second ranges from 10 to 60 s. These increase as flow rate decreases. The sensor response to flow rate was adjusted to remove the effects of ambient temperature fluctuations is shown in Fig. 7. Power consumption and overheat ratio were 36 mW and 1.9%, respectively. The sensor can resolve up to 10 $\mu\text{l}/\text{min}$ flow. Commercial devices with such resolution are not currently available. These results are in agreement with behavior predicted by King's Law, $H(v) = A + B v^{1/2}$, where $A = 0.8559$, $B = -0.878849$, and $n = 0.51$ (Fig. 8).

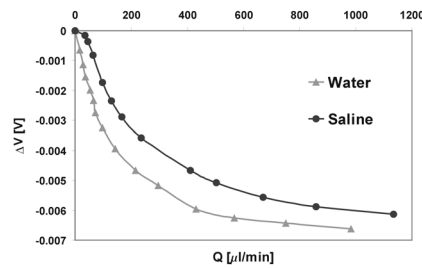


Fig. 7 Sensor Response to Flow

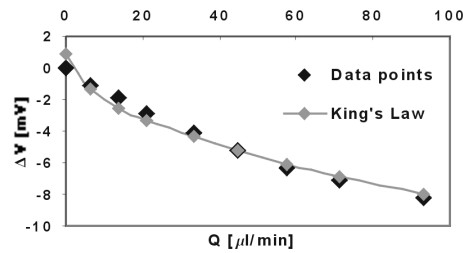


Fig. 8 King's Law vs. Experimental Results

5. Conclusion

A MEMS fluid flow sensor capable of detecting 10 $\mu\text{l}/\text{min}$ flows has been demonstrated. Future work will include testing with different biological fluids, e.g. blood and urine, and various detergents. As many biological fluids contain particulate matter, the effect these have on measurements will also be examined.

Acknowledgements

The authors would like to thank Trevor Roper for help with processing and the NSF Center for Neuromorphic Systems Engineering and IRIS, Inc. for funding.

References

1. Yang, C. and H. Soeberg, *Sensors and Actuators A*, **33**: pp. 143-153, (1992).
2. Lammerink, T.S.J., *et al.*, *Sensors and Actuators A*, **37-38**: pp. 45-50, (1993).
3. Nguyen, N.T. and R. Kiehnscherf, *Sensors and Actuators A*, **49**: pp. 17-20, (1995).
4. Wu, S., *et al.* MEMS 2000, Miyazaki, Japan, (2000).
5. Meng, E., *et al.* Micro Total Analysis Systems 2000, Enschede, The Netherlands, pp. 41-44, (2000).